**W-5920 OSCILLATOR ETCHING SYSTEM**

- Oscillator SMD and VCXO devices are adjusted to target frequency by Ion Beam Etching of the crystal electrode material
- The motional parameters of the crystal remain virtually unchanged
- Up to sixteen parts are processed simultaneously for high system throughput
- Small crystal electrodes are as easy to precisely adjust as large electrodes
- Measured parameters are checked against easy to define Q.C. limits

**SPECIFICATIONS**

- Measurement Range: 32 KHz to 622 MHz
- Etching Performance: ± 1 ppm typical final frequency

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**FACILITY REQUIREMENTS**

- **Power:** 380VAC/208VAC
  - 3-Phase, 7KVA, 50/60 Hz
- **Inlet Pressure:**
  - Air: 90 - 100 PSIG
  - Nitrogen: 90 - 100 PSIG
  - Process Gas: 70 - 100 PSIG
- **Dimensions:** W 53” x D 37” x H 88”

**SYSTEM CONFIGURATION**

- S&A Multi-Function PCI Card
- S&A 250B-1 Network Analyzer
- Direct Drive Roughing Pump
- Diffusion Pump (Cryo Pump Option)
- 690 Elevator System (Optional)
- Ion Gun
- Computer
- System Software
- Light Pole

**SCREEN FORMAT**

![Screen Format Image]

**FACILITY REQUIREMENTS**

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  - 3-Phase, 7KVA, 50/60 Hz
- **Inlet Pressure:**
  - Air: 90 - 100 PSIG
  - Nitrogen: 90 - 100 PSIG
  - Process Gas: 70 - 100 PSIG
- **Dimensions:** W 53” x D 37” x H 88”

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